**Carbon Nanotechnology: Scientific and Technological Issues** Joseph W. Lyding **Department of Electrical and Computer Engineering and Beckman Institute University of Illinois at Urbana-Champaign** 







#### Carbon Nanotechnology: Scientific and Technological Issues Joseph W. Lyding Department of Electrical and Computer Engineering and Beckman Institute University of Illinois at Urbana-Champaign

### <u>Outline</u>

- Carbon Nanotechnology
- SWNTs on Silicon
- SWNTs III-V Semiconductors
- Graphene
- Ultra-Sharp (r < 1nm) STM Probes







### Graphene and Nanotube Nanoelectronics

### Sensors





Nature Mat. 6, 652 (2007).

#### Advantageous properties for nanoelectronics

All Surface -> Good for Sensors

High Mobilities  $\mu = 20,000 \text{ cm}^2/\text{V}\cdot\text{s}$  (Si MOSFET – 600 cm<sup>2</sup>/V·s, InSb – 30,000 cm<sup>2</sup>/V·s)

#### **Bandgap Engineering**

### **Bandgap engineering**



#### Phys. Rev. Lett. 98, 206805 (2007).







# **Carbon Nanotubes**

- Fullerenes discovered by Smalley, Kroto, & Curl 1985 (1996 Nobel prize)
- Nanotubes discovered by Iijima in 1991 can be seen in its structure as an extension of a buckyball
- Most nanotubes are bundled together (by van der Waals interactions), forming ropes









To close the CNT, the cap need pentagons as declination points







# **Carbon Nanotubes - Structure**









### **Electronic Properties of Carbon Nanotubes**



## **STM/STS of SWNTs**





Jeroen W. G. Wildoer, Liesbeth C. Venema, Andrew G. Rinzler, Richard E. Smalley & Cees Dekker, Nature <u>391</u>, 59 (1998).







## **STM of SWNTs**



Teri Wang Odom\*, Jin-Lin Huang\*, Philip Kim, Charles M. Lieber, Nature 391, 62 (1998)







## Single Walled Carbon Nanotubes on Si(100)

•Problems with Solution Deposition •Dry Contact Transfer (DCT) Technique Nanotube-Substrate Interactions



#### Peter Albrecht



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### Ultrahigh Vacuum (UHV) Scanning Tunneling Microscopy (STM)



**Benefits of UHV STM Atomic Resolution Analysis Detailed Spectroscopy Control Surface Chemistry** 

#### Thermal Drift ~ 0.1nm/h @ 300K









## Hydrogen-Passivated Silicon



### Si(100)-2x1:H







# Solution Deposition of SWNTs onto H-Si(100)









# **Results of Solution Deposition of SWNTs**













### Dry Contact Transfer (DCT) Technique











# **Isolated SWNTs Following DCT**



DCT results in the ultra-clean deposition of isolated SWNTs rather than bundles. The DCT method can be generalized for the deposition of nearly any nanostructure onto nearly any surface.







# DCT of SWNTs onto Si(100)-2x1:H





### DCT of SWNTs onto Si(100):H Surfaces









## Semiconducting SWNTs on H-Si(100) characterized by STM spectroscopy



## Metallic SWNTs on H-Si(100) characterized by STM spectroscopy



# Carbon nanotubes can be precisely manipulated on silicon using the UHV STM





(1) Scan across SWNT with feedback ON and store contour (solid line)

(2) Position tip user-specified Δz (typically 5 Å) closer to the surface
(3) Execute manipulation contour with feedback OFF (dashed line)
(4) Optional: interpolate through the SWNT (dotted line)

P. M. Albrecht and J. W. Lyding, Small 3, 146 (2007).







# Nanopatterning H-Si(100)



Lyding et al., Appl. Phys. Lett. 64, 2010 (1994)



Hersam et al., Nanotechnology 11, 70 (2000)









### Controlling Nanotube – Substrate Interactions: STM Nanolithography









### Nanotube-Substrate Interaction H-Passivated vs Clean Si(100)





### Preferential orientation of a semiconducting tube on STMpatterned H-Si(100)



P. M. Albrecht, S. Barraza-Lopez, and J. W. Lyding, Small 3, 1402 (2007).









### SWNT zigzag symmetry aligns parallel to Si dimer rows



P. M. Albrecht, S. Barraza-Lopez, and J. W. Lyding, Small 3, 1402 (2007).



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### Nanotube Electronic Structure: Influence of Local Charge



# Individual SWNTs can be cut with the STM under feedback control



#### Single molecule absorption spectroscopy detected by STM Erin Carmichael, Josh Ballard, Dongxia Shi, Greg Scott, Martin Gruebele



### SWNTs on UHV-Cleaved GaAs(110) and InAs(110)

- Nanotube-Substrate Alignment
- NT-NT Metal-Semiconductor Junction
- Nanotube-Substrate Electronic Interactions









# DCT of SWNTs onto the III-V(110) Surface

#### **DCT Process**







19.5 nm, 15 pA, 1.7 V

L. B. Ruppalt, P. M. Albrecht and J. W. Lyding, JVST B22, 2005 (2004).







### SWNTs Preferentially Align Along Lattice Rows



### SWNTs Preferentially Align Along Lattice Rows



19.5 nm, 15 pA, 1.7 V



Yong-Hyun Kim, M. J. Heben, and S.B. Zhang, *PRL*, **92**, 176102-1 –4 (April 2004)











### SWNTs on InAs(110): Substrate-Induced NT Doping





### SWNTs on InAs: Orientation-Dependent Effects







### SWNTs on InAs: Orientation-Dependent Effects



### SWNTs on InAs: Orientation-Dependent Effects



## Nanotube Heterojunction on InAs(110)



L.B. Ruppalt and J.W. Lyding, Small 3, 288 (2007)







# SWNT IMJ Identified via STM



# STM of intramolecular SWNT junction (IMJ)





L.B. Ruppalt and J.W. Lyding, Small 3, 288 (2007)





# Spatially Resolved STS indicate MIGS at IMJ











# Spatially Resolved STS indicate MIGS at IMJ



### Spatially Resolved STS indicate MIGS at IMJ





L.B. Ruppalt and J.W. Lyding, Small 3, 288 (2007)



ECE Illinois

### Graphene

# Finite Size EffectsSubstrate Electronic Effects



### Kyle Ritter, Justin Koepke



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# Single Layer Graphene











## **Double Layer Graphene**









### Graphene Spectroscopy: Finite Size Effect



### Graphene energy gap scales inversely with length









### **Graphene: Substrate Effects**



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### **Graphene:** Substrate Effects









### Nanotube-Substrate Interaction Substrate Structure Superimposed on Nanotube









### Ultra-Sharp (r < 1nm) STM Probes

Field-Directed Sputter Sharpening (FDSS)
Tungsten and Platinum-Iridium Probes
STM Measurements



### Field-Directed Sputter Sharpening (FDSS)

Apply Positive Bias to Probe to Deflect Ions away from Apex
Material Surrounding Apex is Preferentially Sputtered – Sharpening Apex
Sharpened Apex Enhances Field-Directed Process, ultimately leading to Self-Limited Sharpness (r < 1 nm)</li>



#### Note: FDSS is compatible with batch processing.







### PtIr Probe: Incremental Sharpening









### Sharpening: TEM Imaging



### STM Imaging





Poly-Tungsten Tip Bias: +400 V 2.0 keV Neon Ions 35 minutes





# STM Patterning









# In conclusion...



•The DCT technique enables the ultra-clean fabrication of carbon nanotubes and graphene on clean semiconductor surfaces.

•Atomic scale STM and STS elucidates the detailed nature of the nanostructure-substrate interaction.







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